

FIG. 1

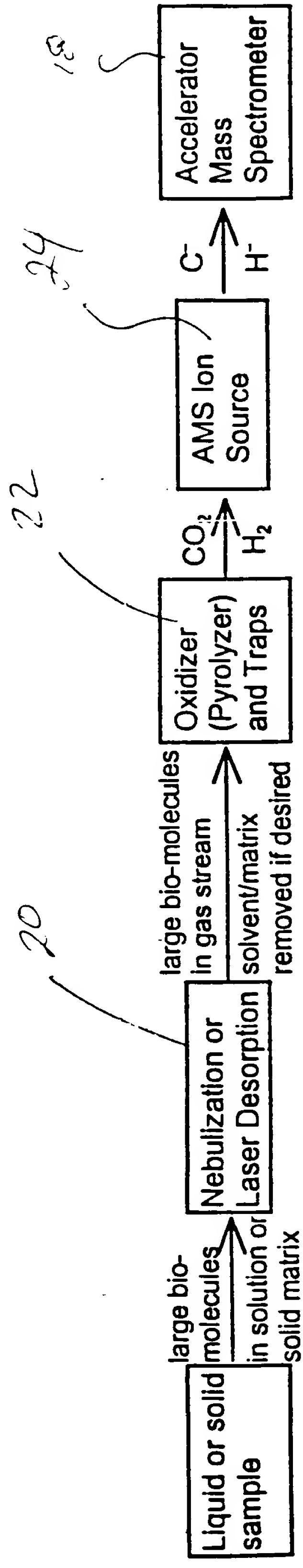


FIG. 2

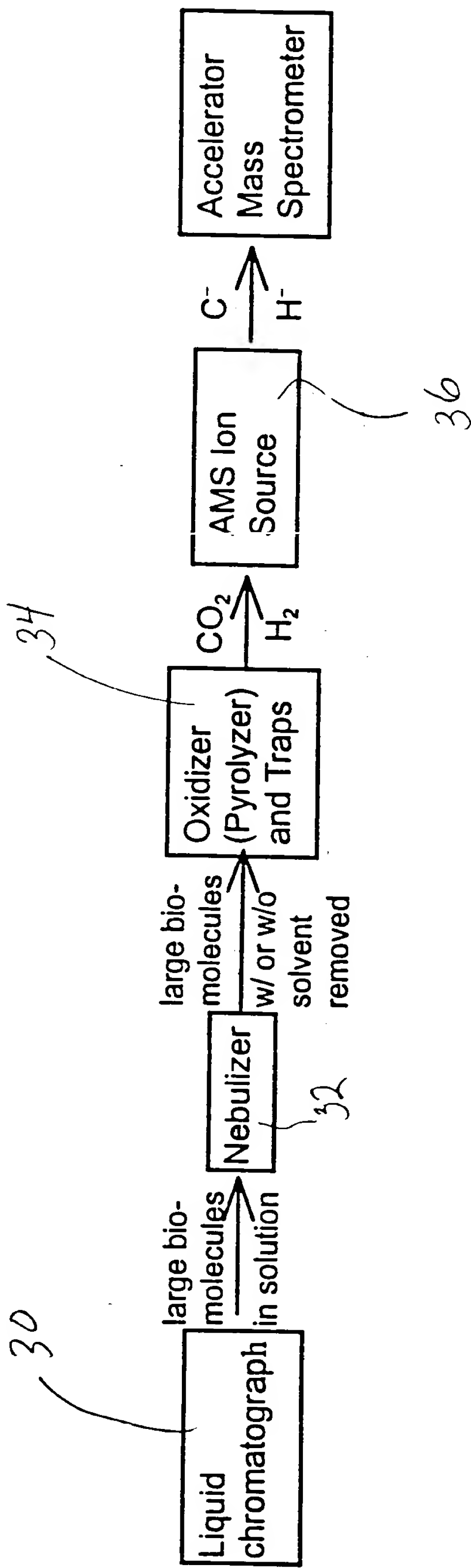


FIG. 3

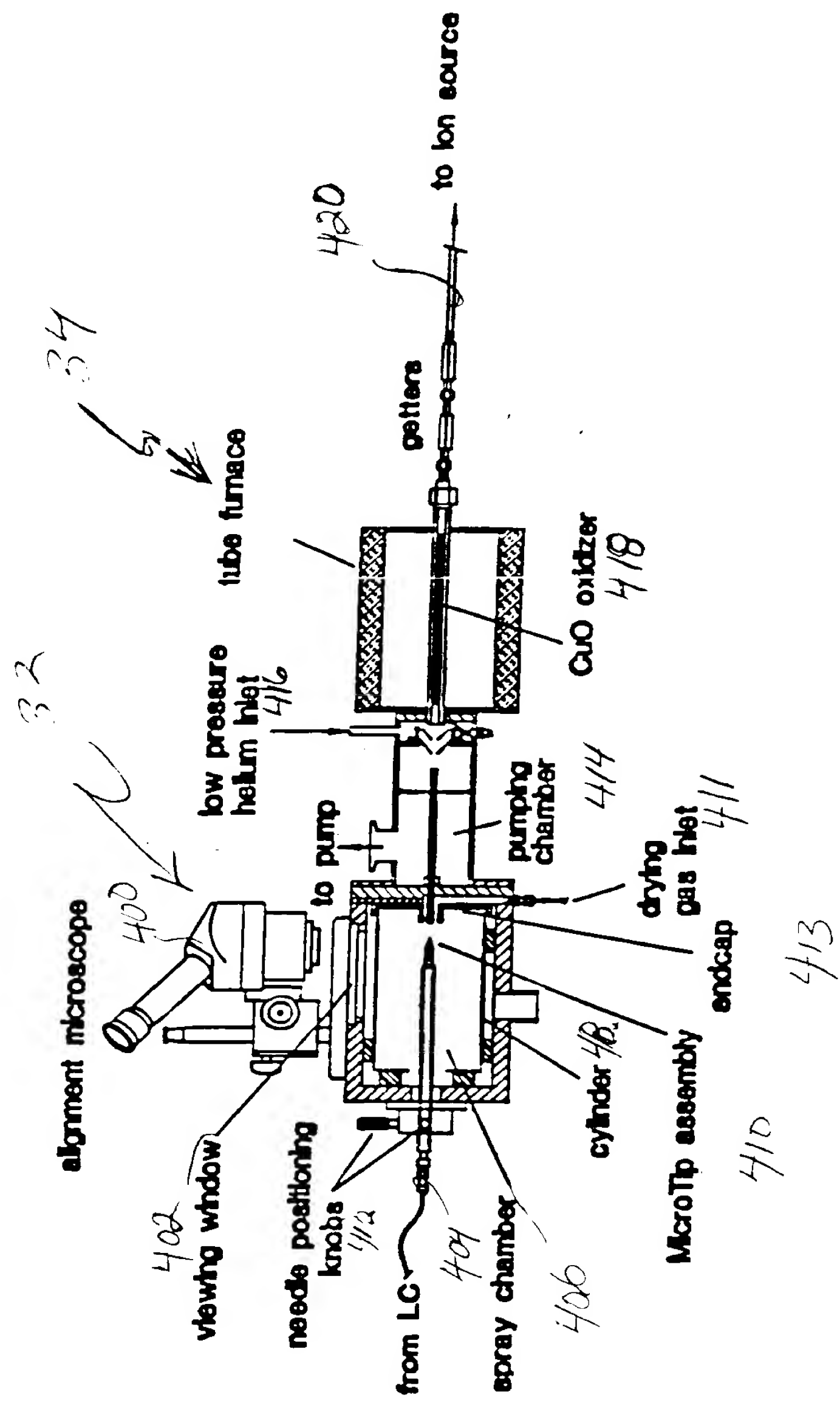


FIG. 4A

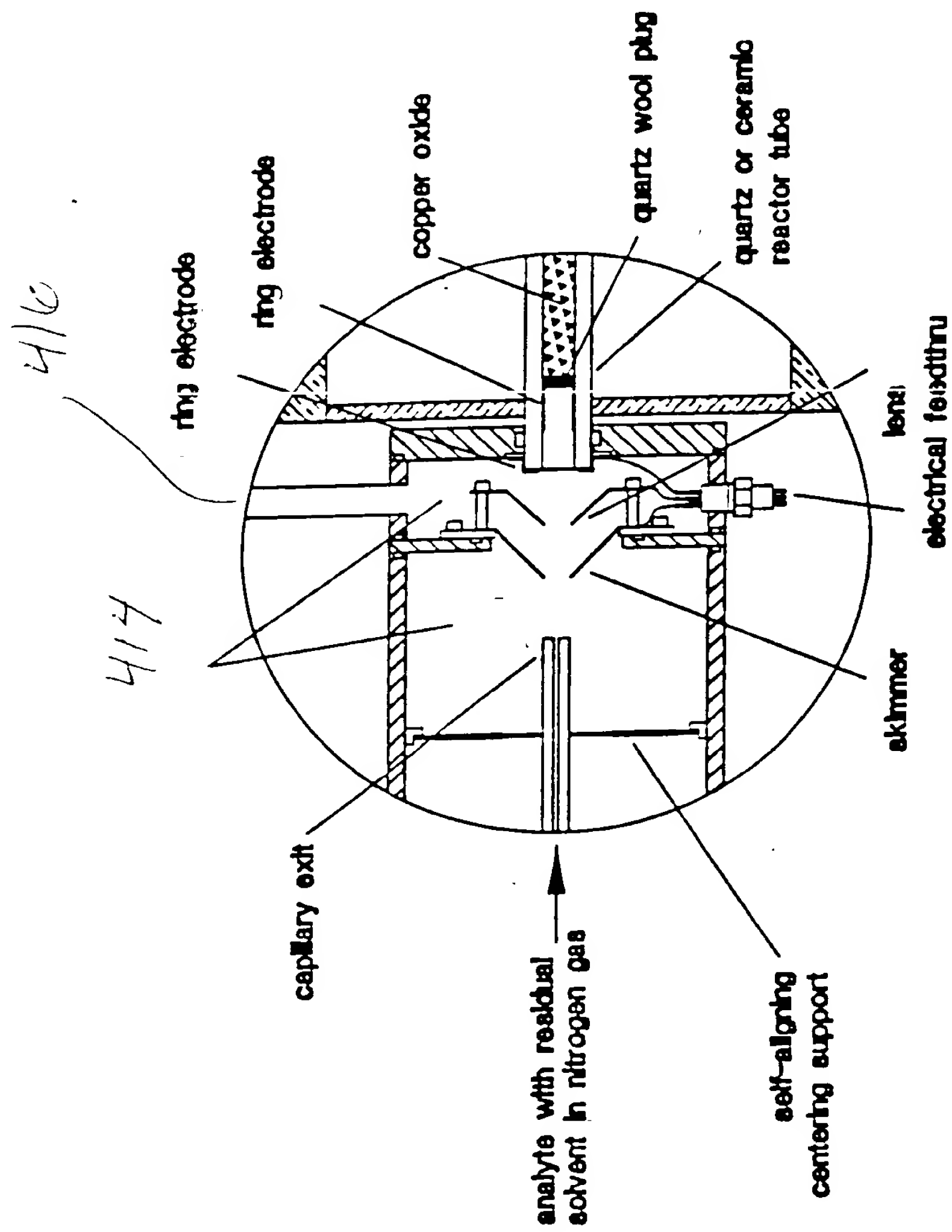


FIG. 4B

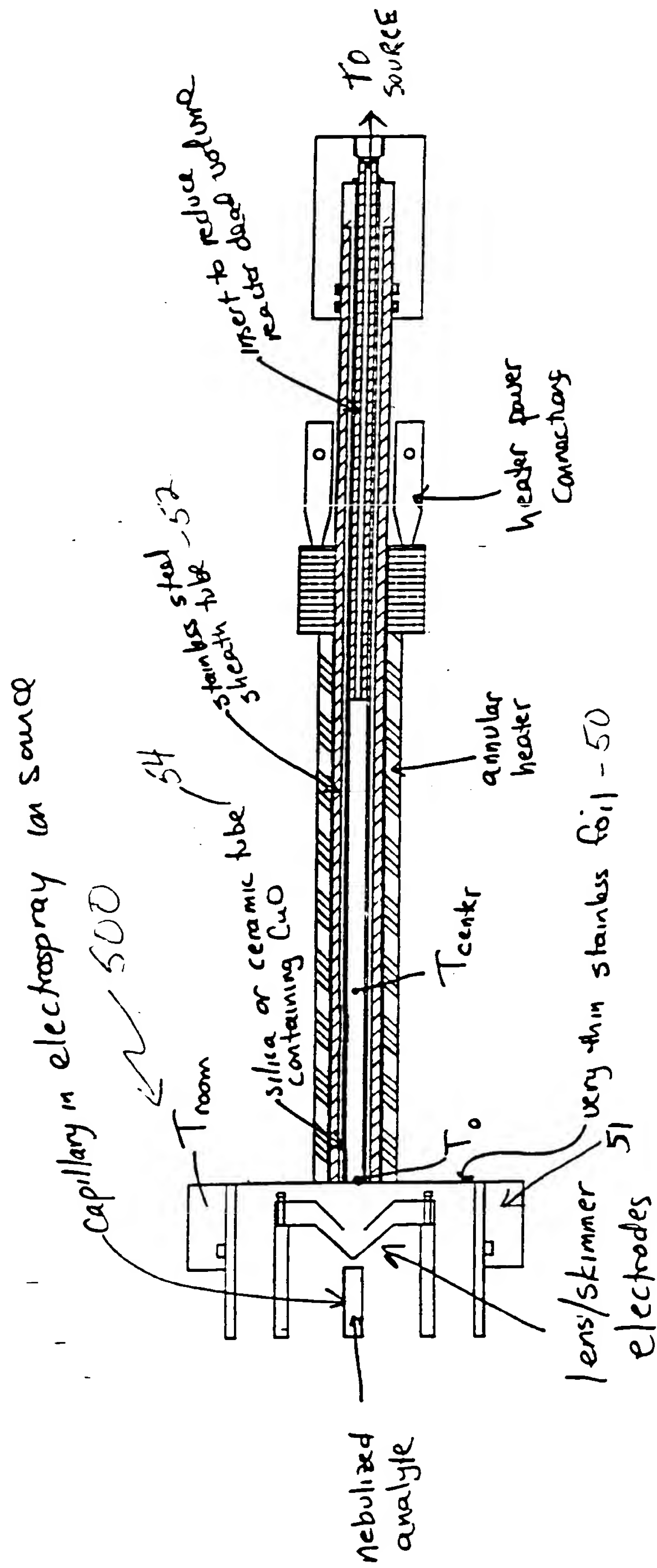


FIG. 5

FIG. 6B

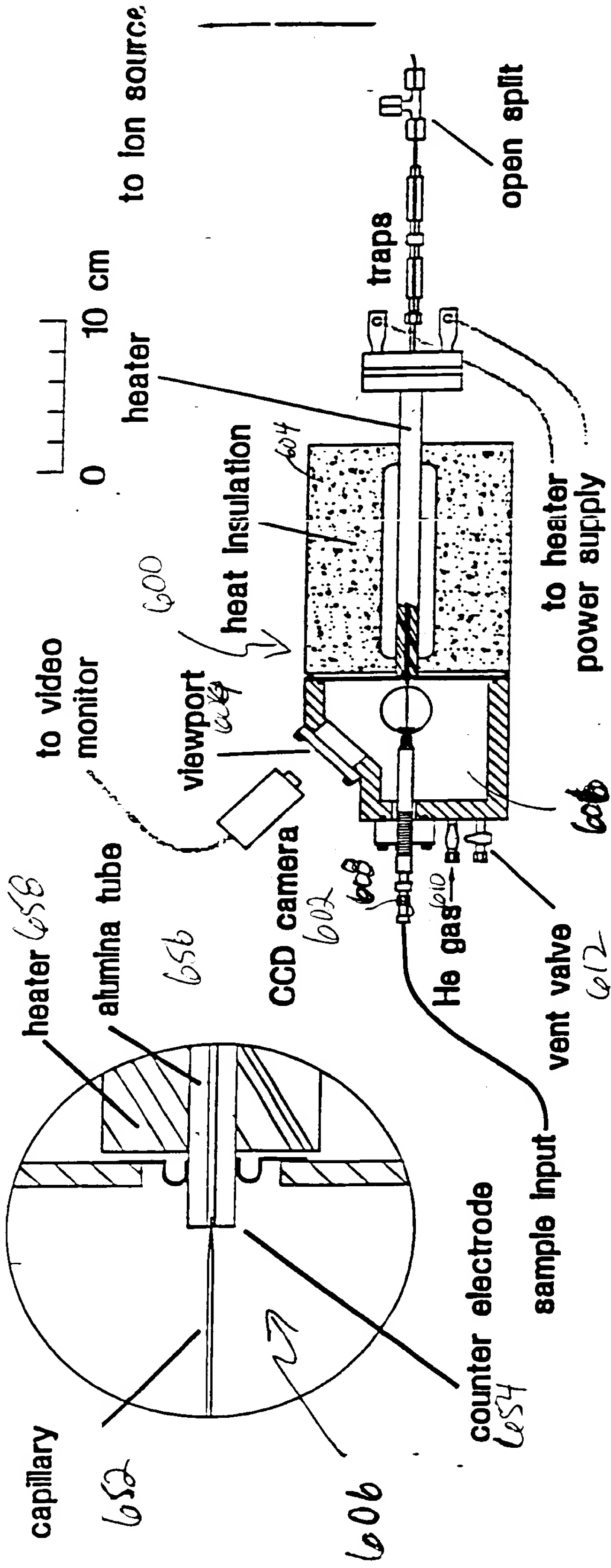


FIG. 6A

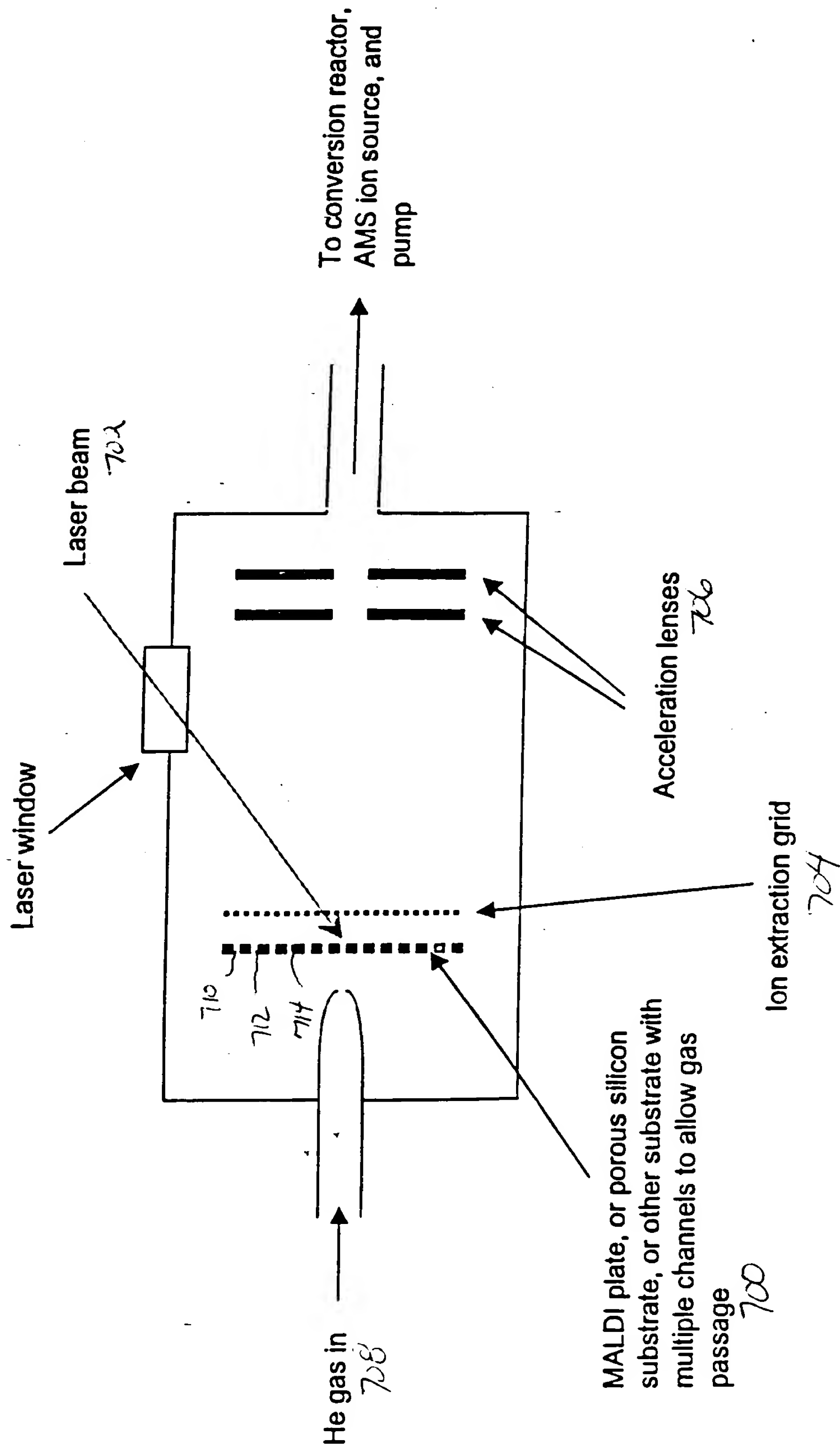


FIG. 7



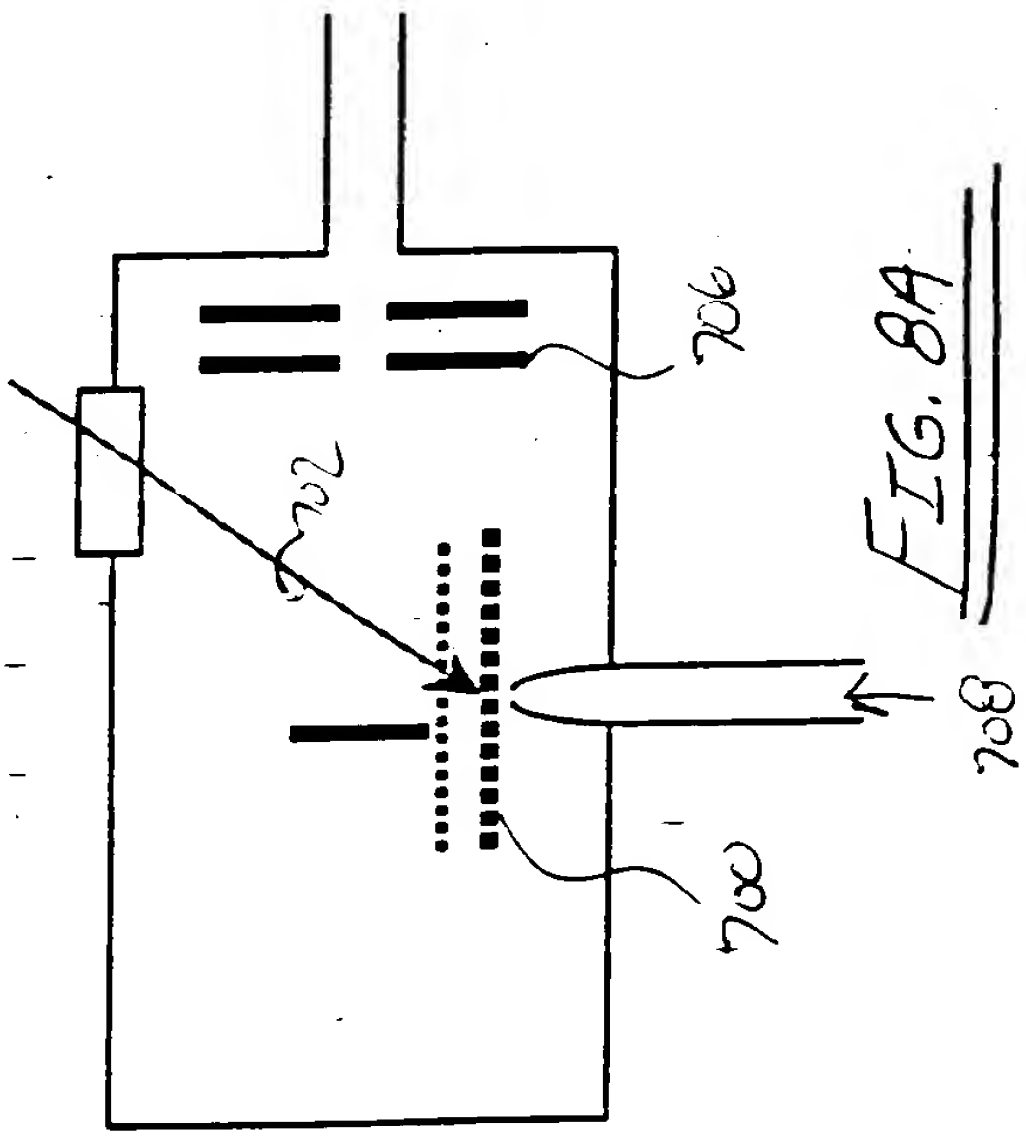


FIG. 8A

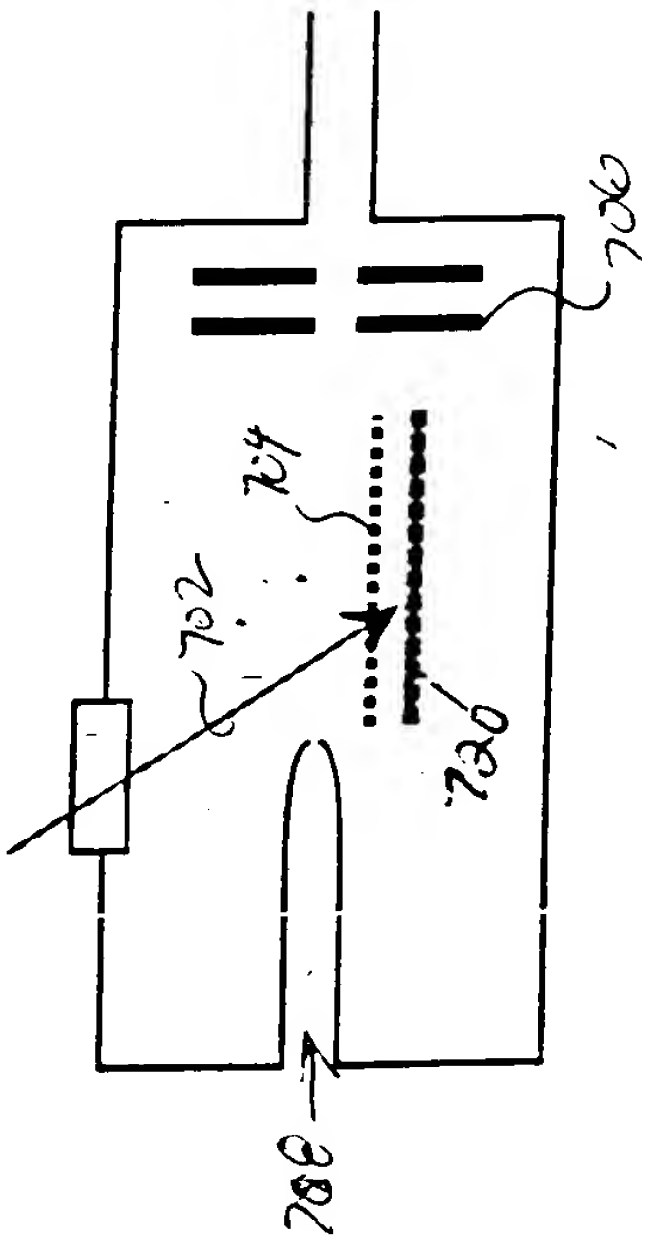


FIG. 8B

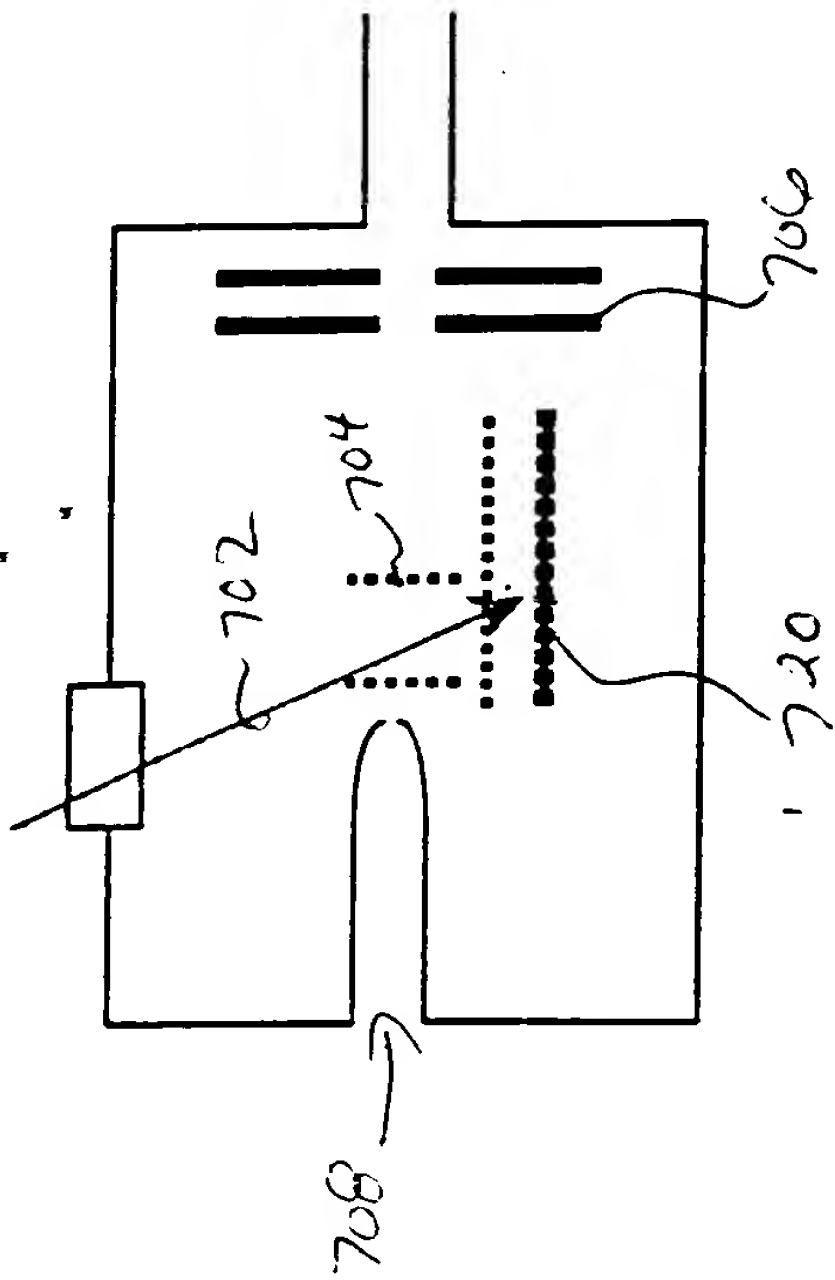


FIG. 8C

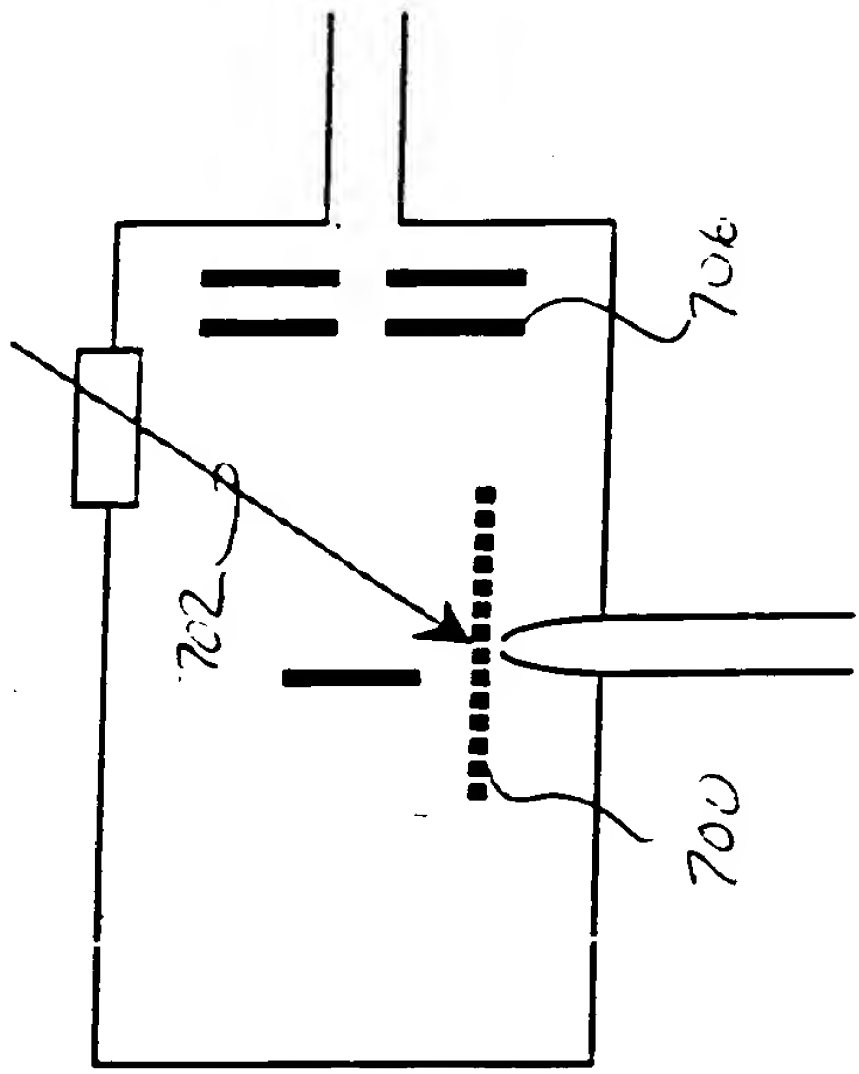


FIG. 8D

Sample dispensing  
apparatus

Sample input

Sample bed

substrate

Sample applied  
to sample bed

**Sample deposition**

FIG. 9A

Laser beam

Converted  
chemical form

Sweep gas in

**Laser-induced conversion**

FIG. 9B

Pipetter

Sample input  
(e.g. HPLC eluent)

Refractory substrate

Thin layer of  
CuO catalyst

Sample applied  
to CuO bed

**Sample deposition**

FIG. 10A

Laser beam

CO<sub>2</sub> in He  
to AMS ion source  
or other apparatus

He gas in

**Laser-induced combustion**

FIG. 10B

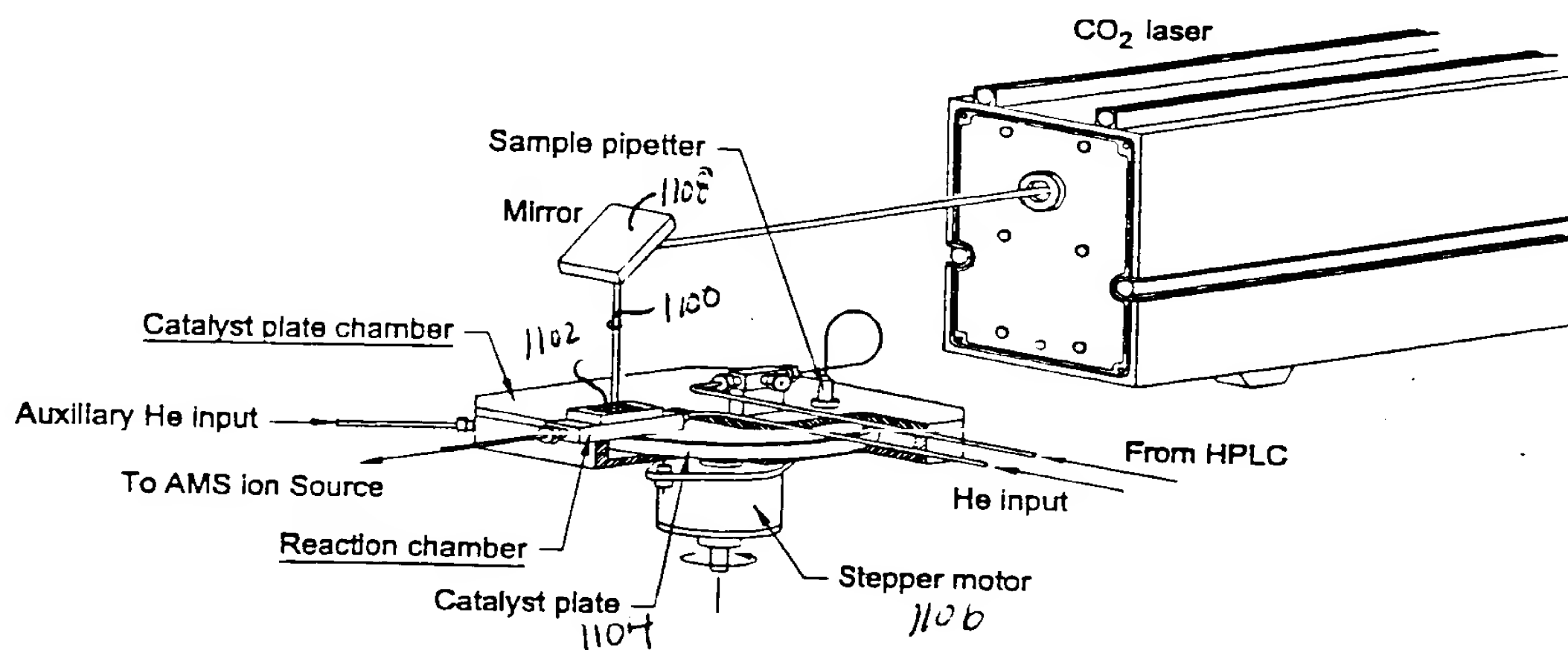


FIG. 11A

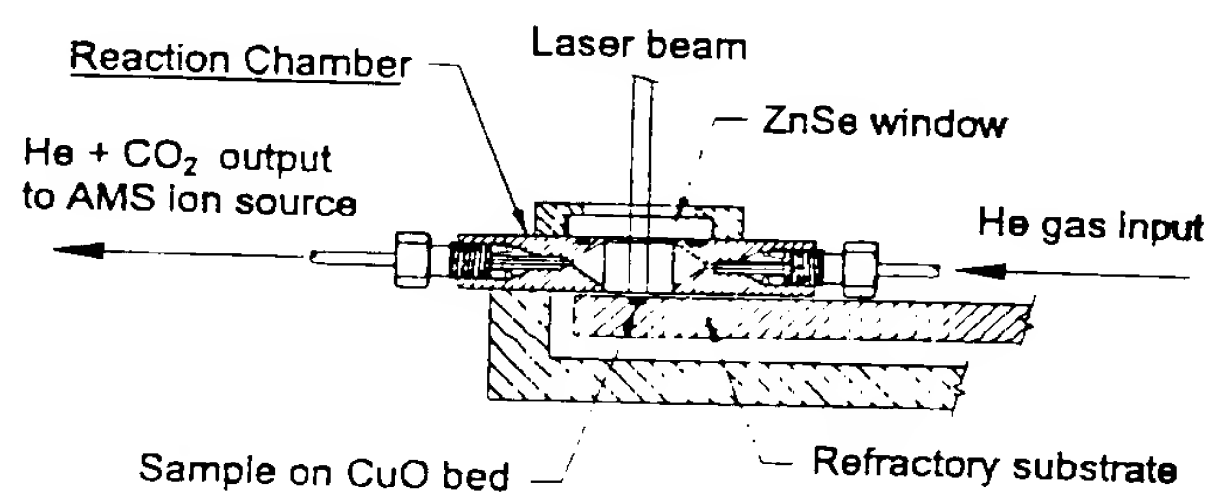


FIG. 11B

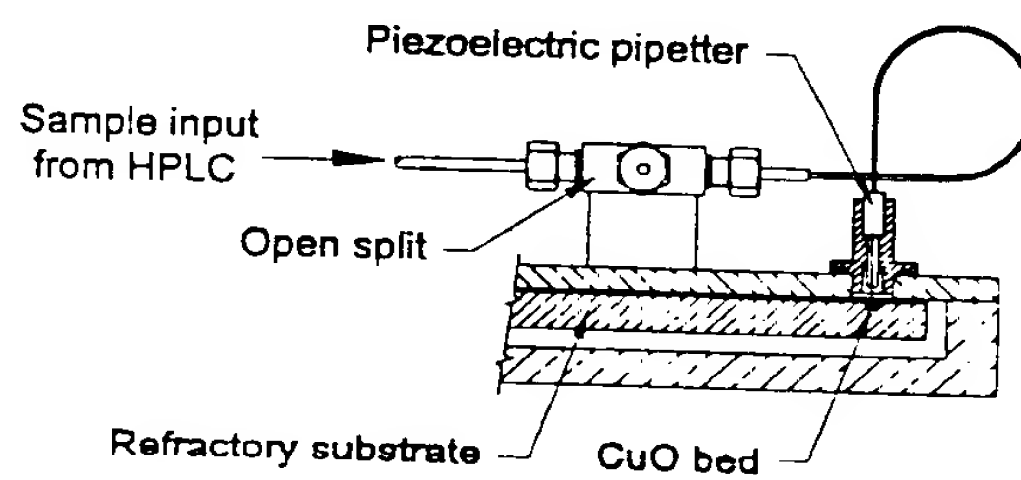


FIG. 11C

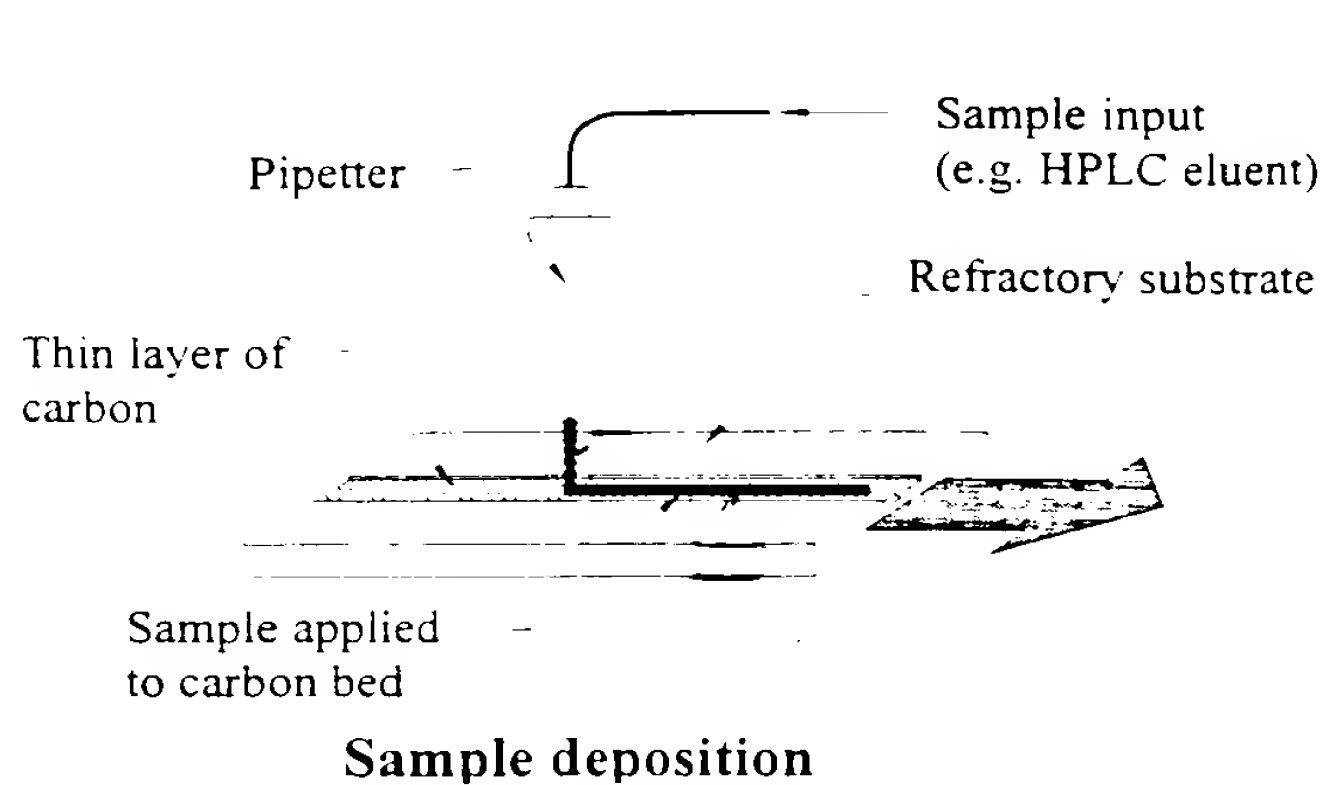


FIG. 12A

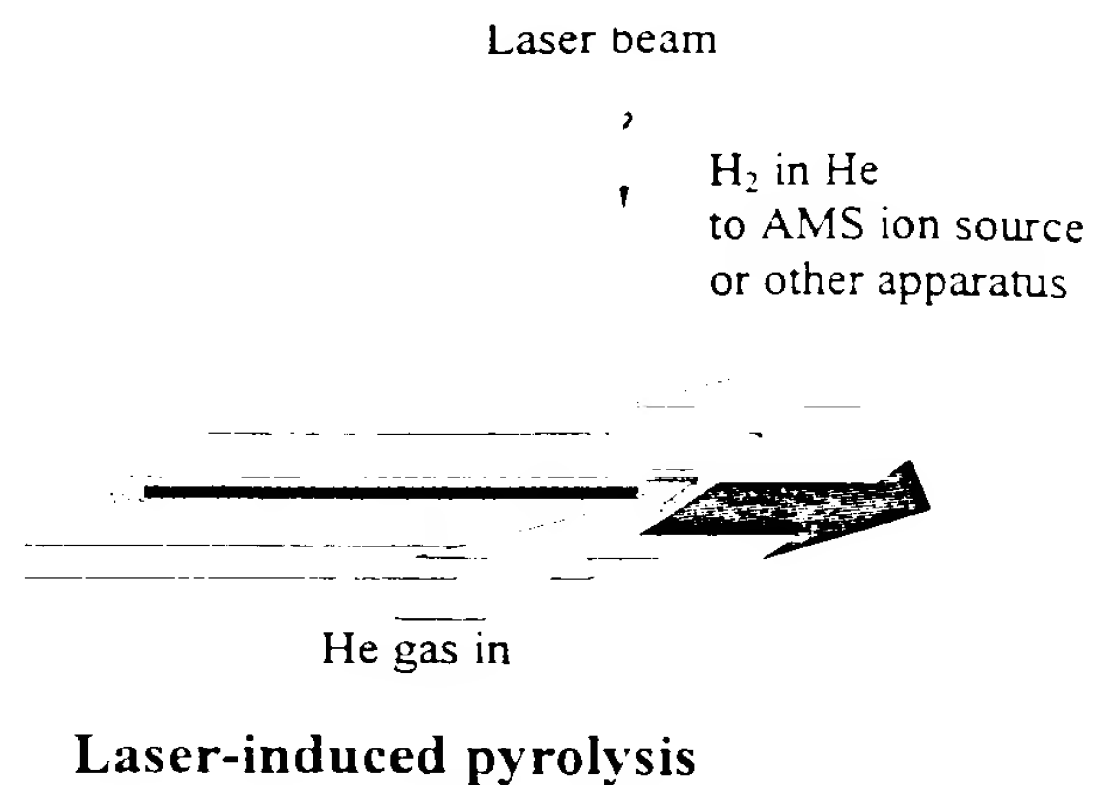


FIG. 12B

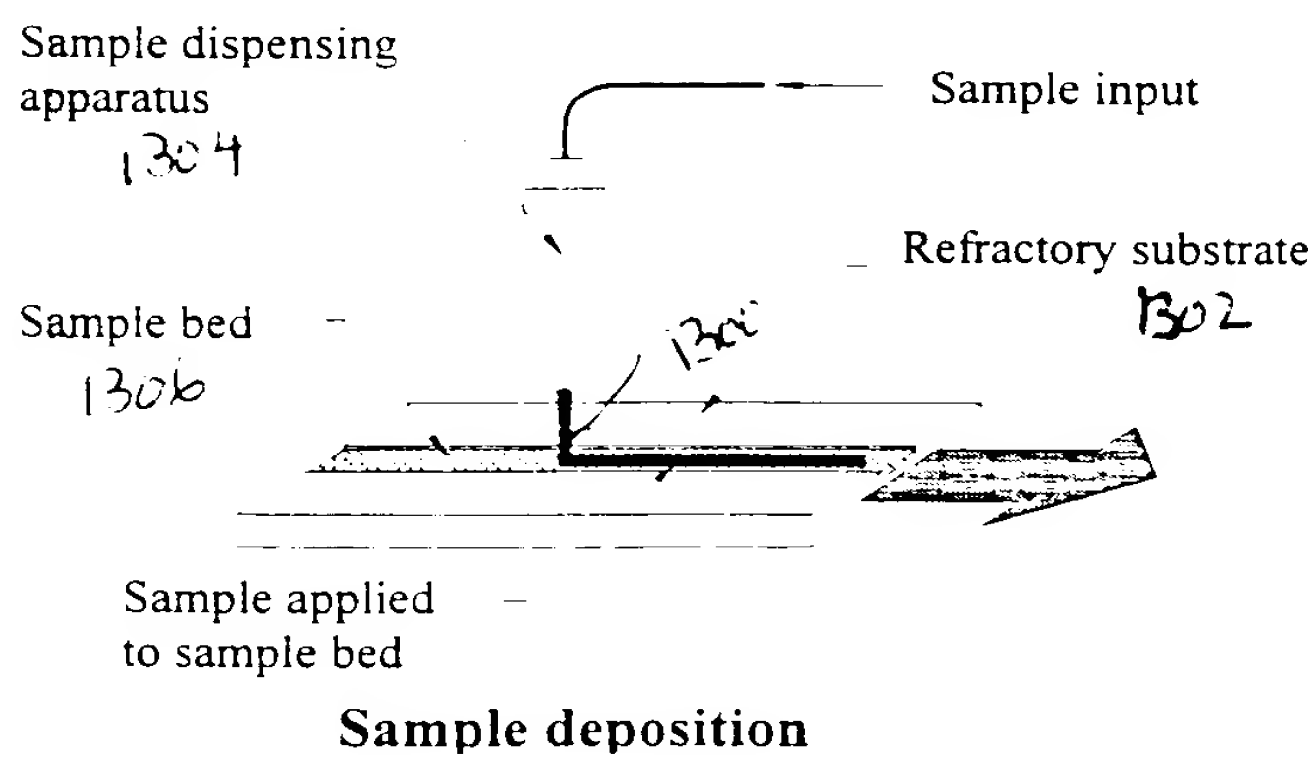


FIG. 13A

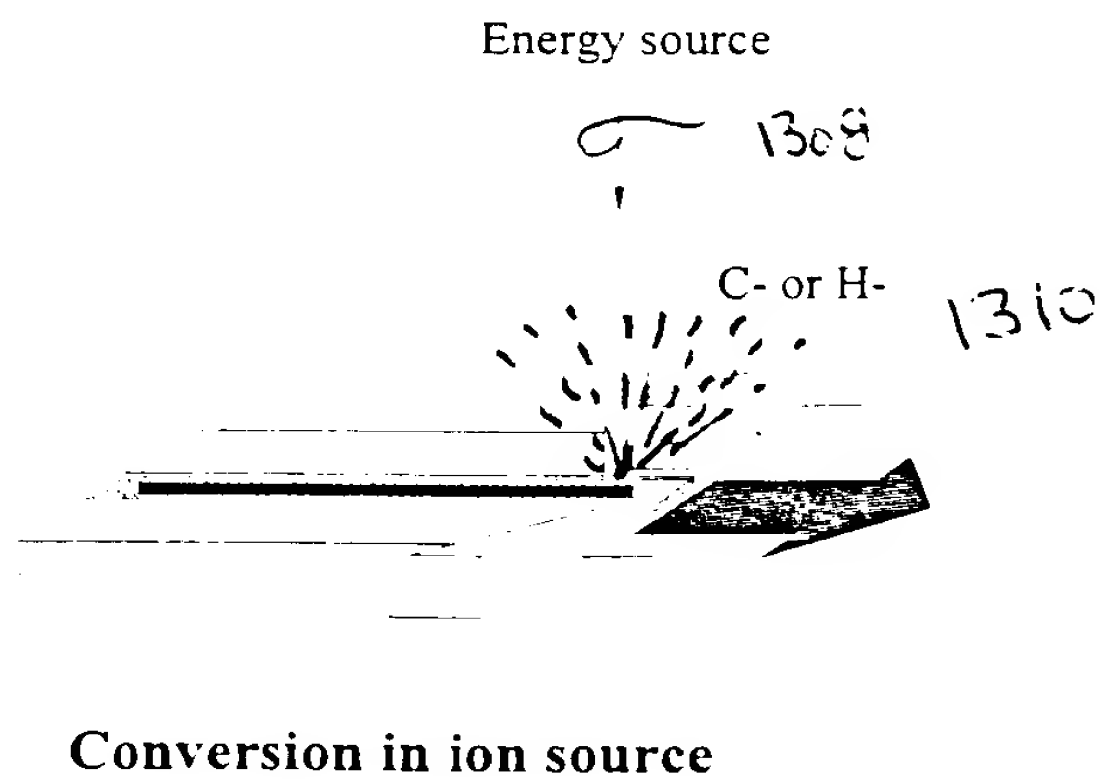


FIG. 13B

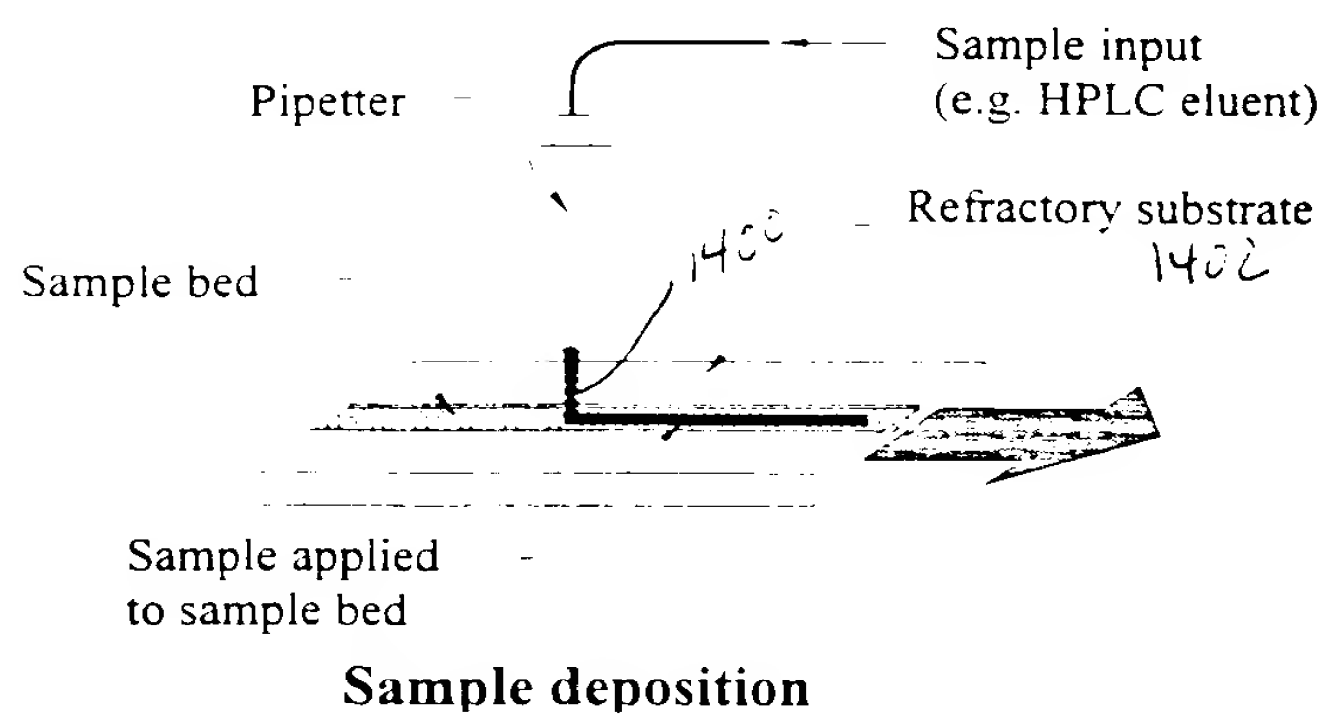


FIG. 14A

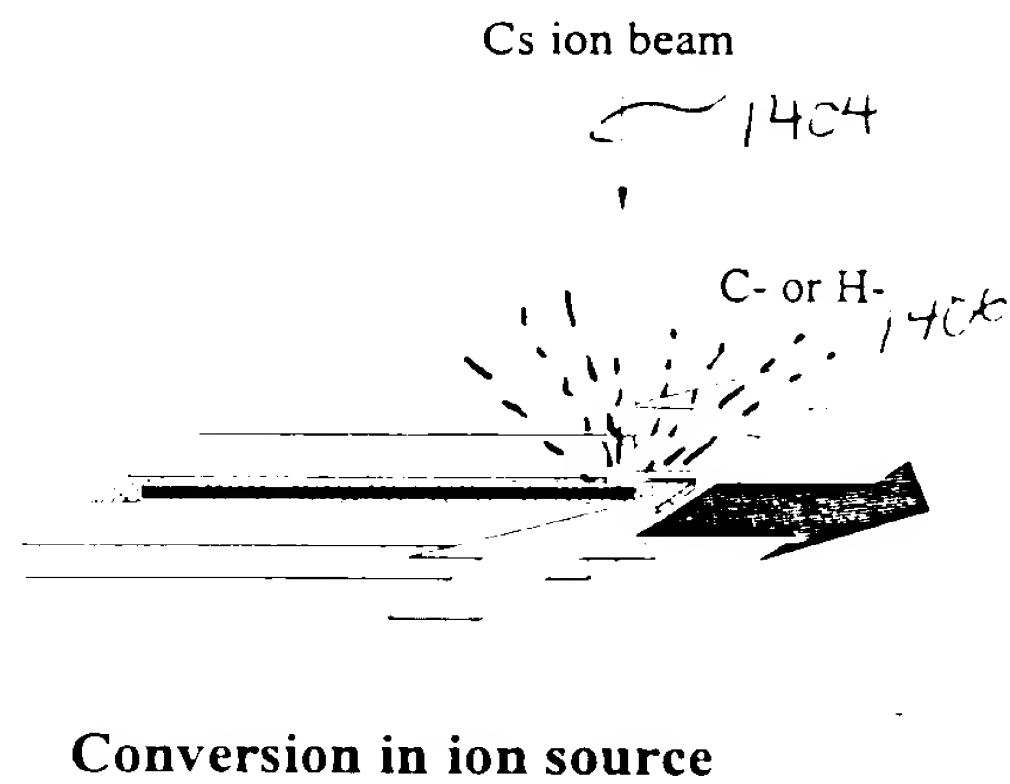


FIG. 14B

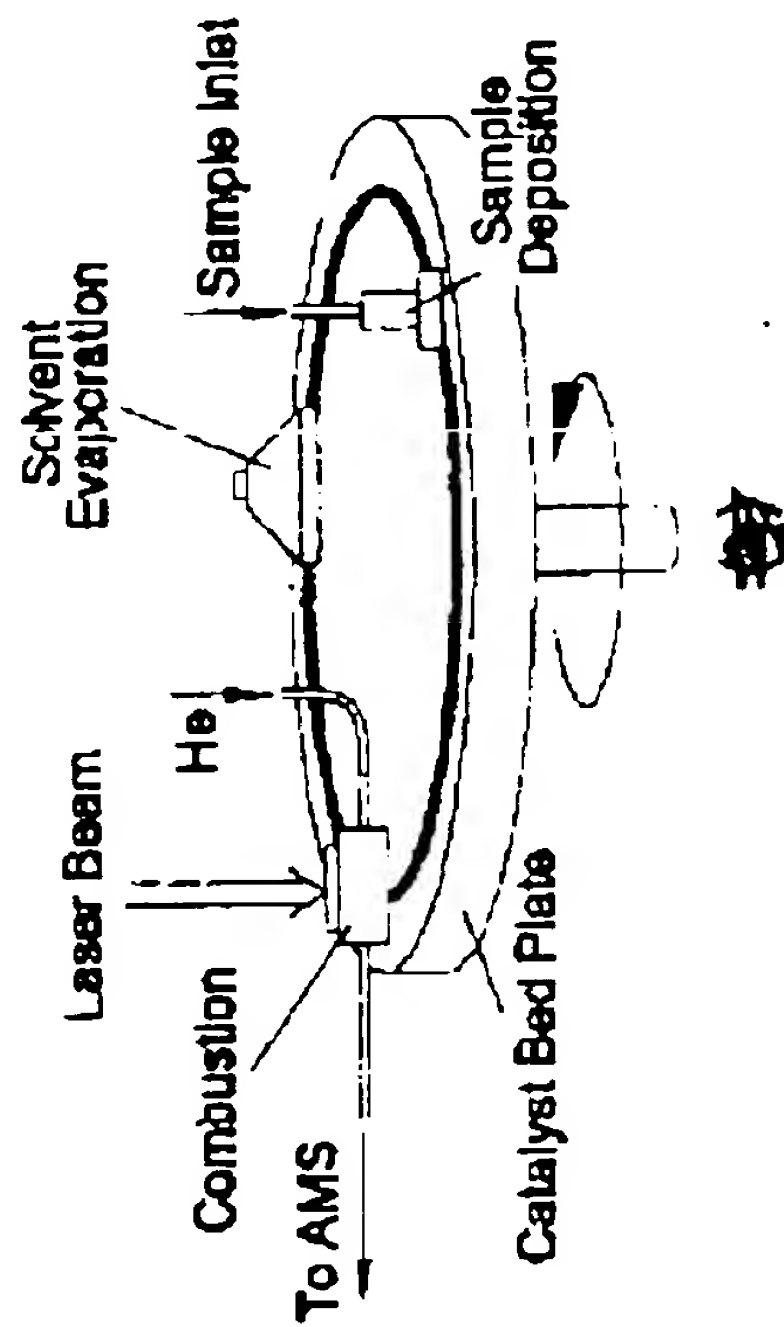


FIG. 15

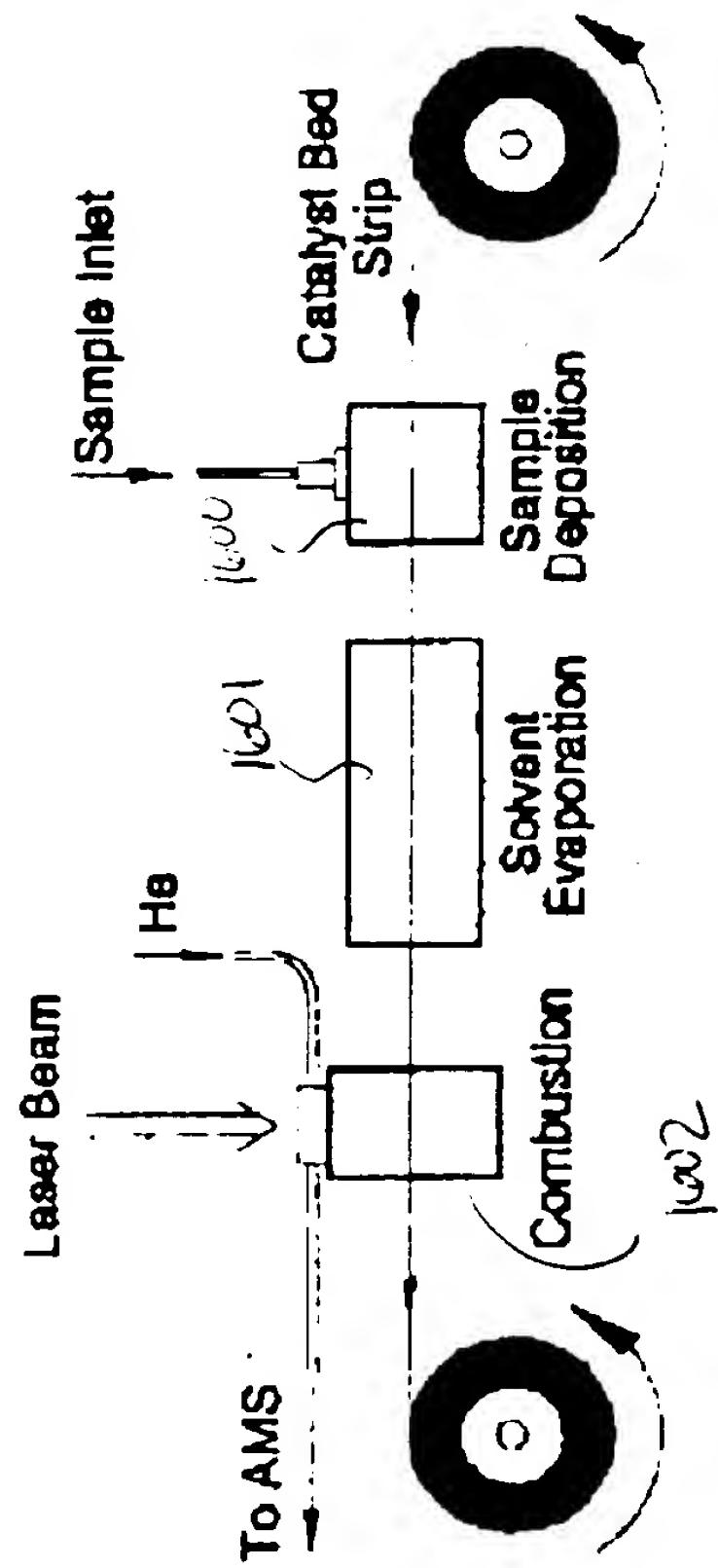


FIG. 16